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Introduction

Applied Optics and Photonics, China (AOPC2015) is the annual conference of the Chinese Society for Optical Engineering, and it is also the largest academic and industrial event in the field of optical and optoelectronic technology in China. The AOPC2015 organization committee intended to build a cohesive platform for academic exchanges, industry exhibitions, and corporate negotiations. The conference had 7 themes, which included 22 technical conferences and 600 technical presentations. We sincerely hope that the research and development of optoelectronic technology was promoted, and that the international cooperation of the optical and optoelectronic industry was enhanced.

AOPC2015 was sponsored by the Chinese Society for Optical Engineering; SPIE, the Optical Society, the European Optical Society, and the Optical Society of Korea were technical co-sponsors. There were also 28 cooperating organizations that supported the conference. We received a total of 1,219 contributions from more than 15 countries, including: the United States, the United Kingdom, Germany, France, Spain, Australia, Canada, Mexico, Brazil, Japan, Republic of Korea, Thailand, Singapore, Russian Federation, and China. Nearly 700 submissions were accepted for the *Proceedings of SPIE*, and over 150 invited talks and papers were suggested to be published in Journals indexed by SCI and Ei. After careful discussion, we selected five plenary speeches, which were presented by famous scientists from the United States, the United Kingdom, Republic of Korea, Japan, and China. There were 205 invited talks in 12 of the technical conferences. On behalf of the organization committee of AOPC, I express thanks to all of the invited speakers and authors for their contributions to and support of the conference.

To celebrate the International Year of Light 2015, we set up 12 display boards highlighting IYL in the exhibition area on the first level. These display boards were to educate the public about light and the applications of light in society.

Finally, on behalf of Prof. Songlin Zhuang, the other co-chairs, and the organization committee of AOPC, I would like to heartily thank our sponsors and cooperating organizations for all they have done for the conference. I thank all of the participants and friends for their interest and efforts in helping us make the conference a success. I also thank the program committee for their effective work and valuable advice—especially the AOPC2015 secretariat and the SPIE staff for their tireless effort and outstanding services in preparing the conference and publishing the proceedings.

Again, we extend our warmest greetings to you and hope you had a pleasant and exciting stay in Beijing!

Guofan Jin